

TEMPERATURE MEASUREMENT ASSEMBLY, SUBSTRATE PROCESSING
APPARATUS, METHOD OF PROCESSING SUBSTRATE, METHOD OF
MANUFACTURING SEMICONDUCTOR DEVICE, AND PROGRAM

ABSTRACT

There is provided a technique that enables stable temperature measurement for a long period under a high-temperature environment. It includes (a) an insulating tube with two through-holes, through which two conductive wires of a temperature sensor are respectively inserted, (b) a first protective tube, through which the insulating tube is inserted inwardly from a first end thereof, (c) a cylindrical sleeve airtightly connected to the first end of the first protective tube and airtightly installed to an installation port from an outside of a furnace, and (d) a second protective tube mounted to the installation port from a furnace and covering the entire first protective tube on the inside of the furnace.

Fig. 2